



Attorney Docket: 029368.50324US
PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: SHINCHIRO YAGI
Serial No.: 09/914,044 Group Art Unit: 2851
Filed: DECEMBER 11, 2001 Examiner: Fuller, Rodney Evan
Title: INSPECTION OBJECT SILICON WAFER FOR THE PURPOSE
OF DETECTING CRYSTAL DEFECTS AND THE METHOD OF
DETECTING THEREOF

PETITION FOR EXTENSION OF TIME UNDER 37 C.F.R. 1.136(a)

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Applicant hereby requests that the period to take action in the above-captioned application be extended by one month pursuant to the provisions of 37 C.F.R. 1.136(a).

A check in the amount of \$110.00 is submitted herewith in payment of the required extension fee. This amount is believed to be correct, however, the Commissioner is hereby authorized to charge any deficiency, or credit any overpayment, to Deposit Account No. 05-1323 (Docket #029368.50324US).

November 5, 2003

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110.00 OP

Respectfully submitted,

J. D. Evans

Registration No. 26,269

Lawrence E. Carter

Registration No. 51,532

CROWELL & MORING, LLP
P.O. Box 14300
Washington, DC 20044-4300
Telephone No.: (202) 624-2500
Facsimile No.: (202) 628-8844

JDE:LEC